

## **Claims**

We claim:

1. A method of monitoring a manufacturing sub-process, the method comprising the steps of:
  - a) providing a KPI platform with a SPC subsystem;
  - 5 b) collecting and storing at least one piece of data on a single database through at least one data collecting apparatus;
  - c) setting at least one range of specifications for the at least one piece of data on the KPI platform;
  - d) accessing the single database with the KPI platform; and
  - 10 e) notifying a user through the SPC subsystem in real time when the at least one sample falls outside the at least one range of specifications.